

Figure 2-20 Transfer characteristics for ECT TFT's before and after 1hr NH_3 plasma passivation

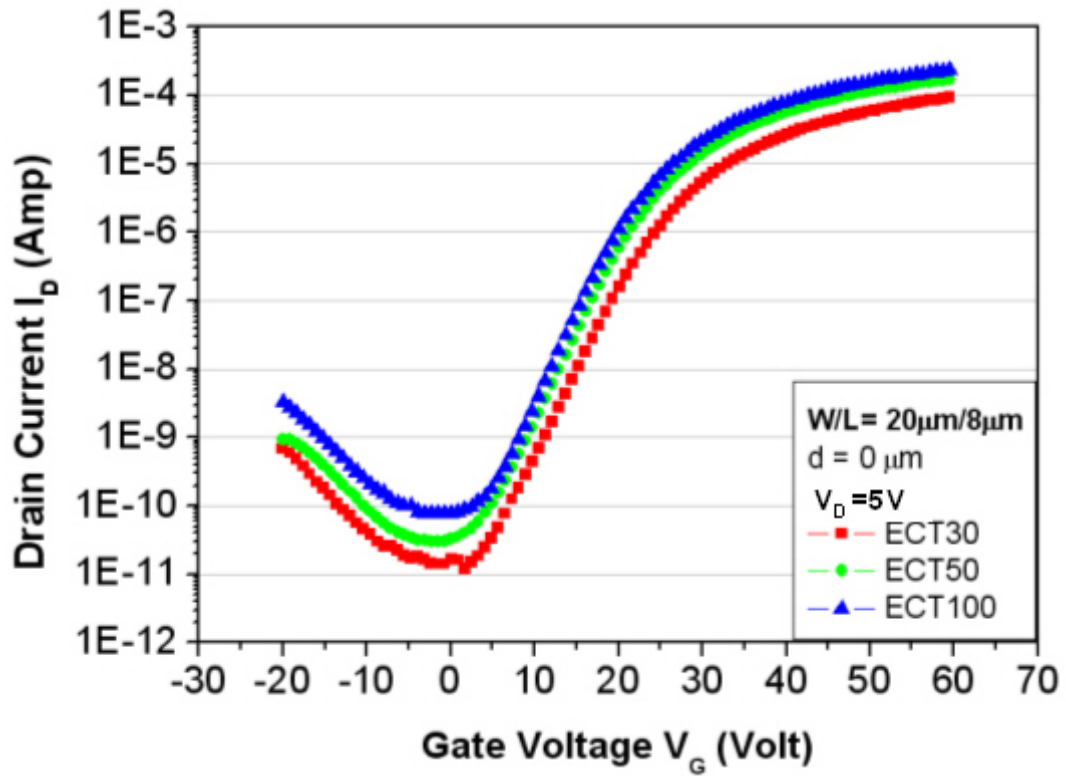


Figure 2-21 $I_D - V_{GS}$ curves of ECT structure with different thickness of the active layer after passivation

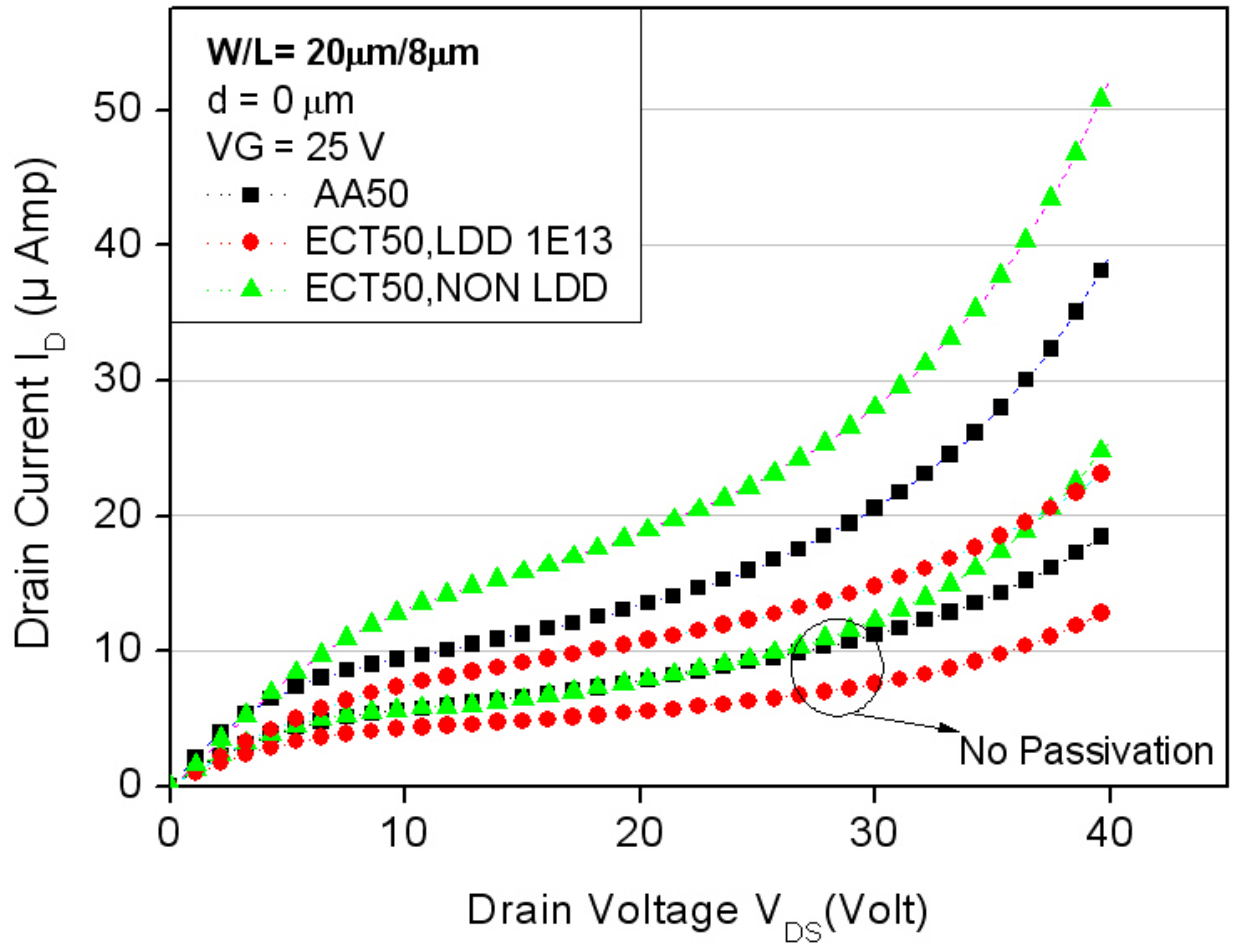


Figure 2-22 I_D - V_D curves extracted at V_G = 25 V for various TFT samples, before and after 1hr NH₃ plasma passivation

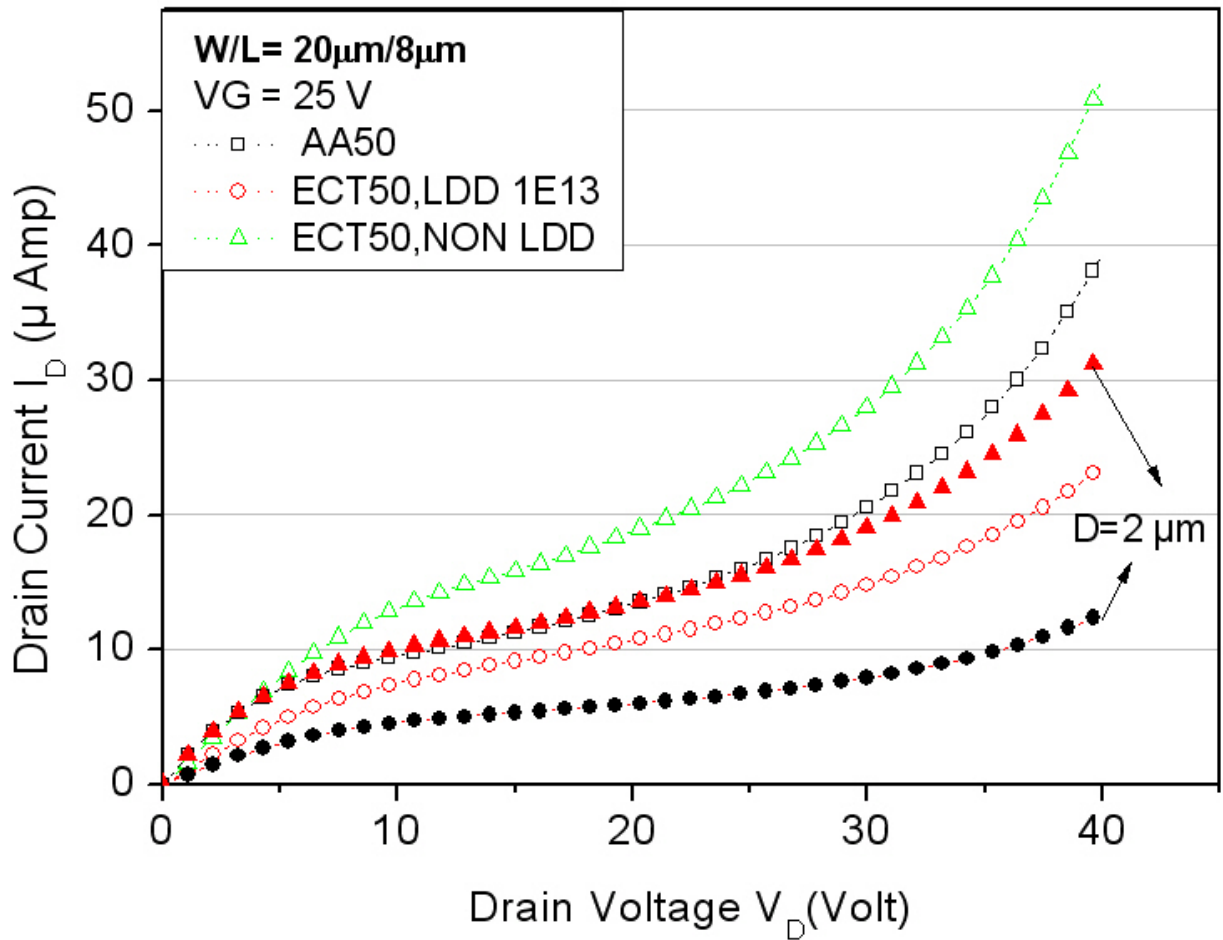


Figure 2-23 $I_D - V_D$ curves extracted at $V_G = 25$ V for various TFT samples: (a) $W/L = 20/8$, $d = 0$ μm, and $d = 2$ μm, after 1hr NH_3 plasma passivation

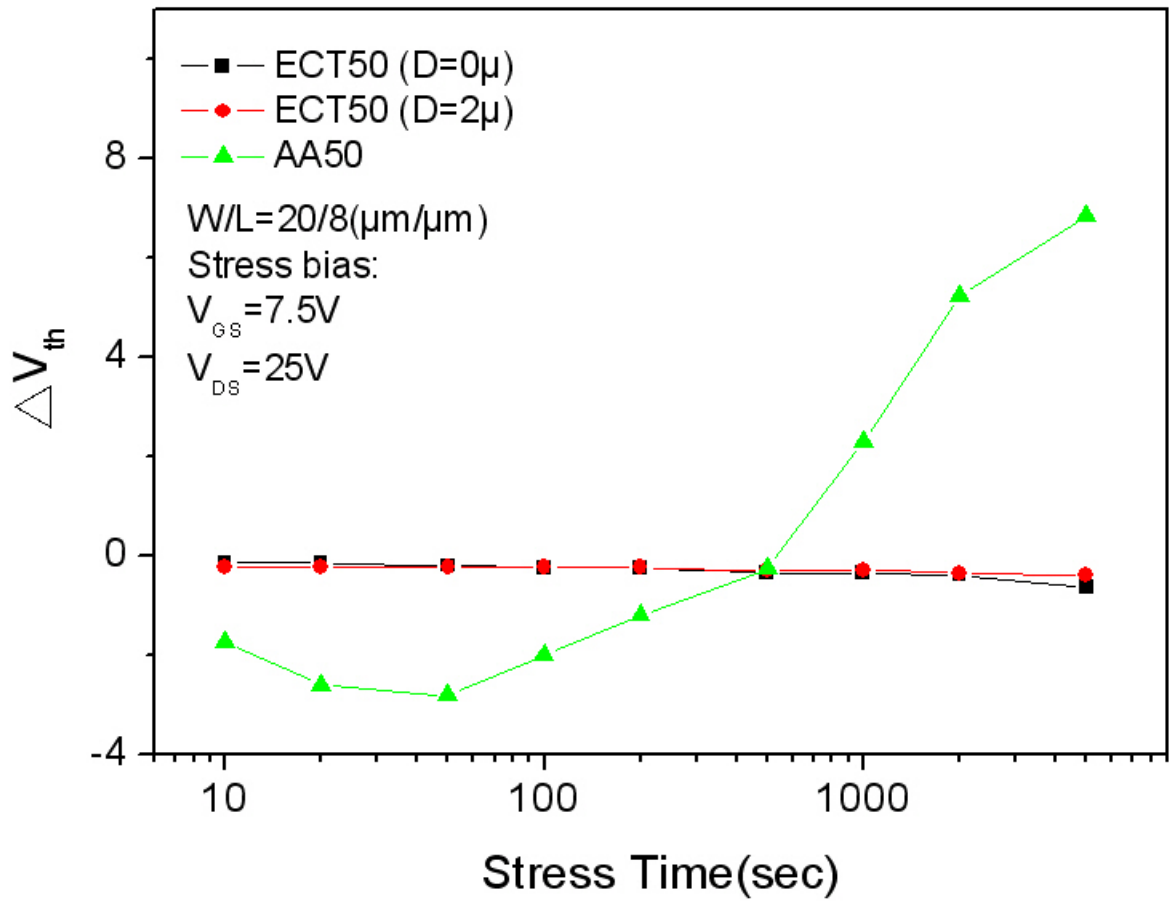


Figure 2-24 Variation of threshold voltage at $V_{DS}=5\text{V}$ under hot carrier stress. D is gate overlapping length.

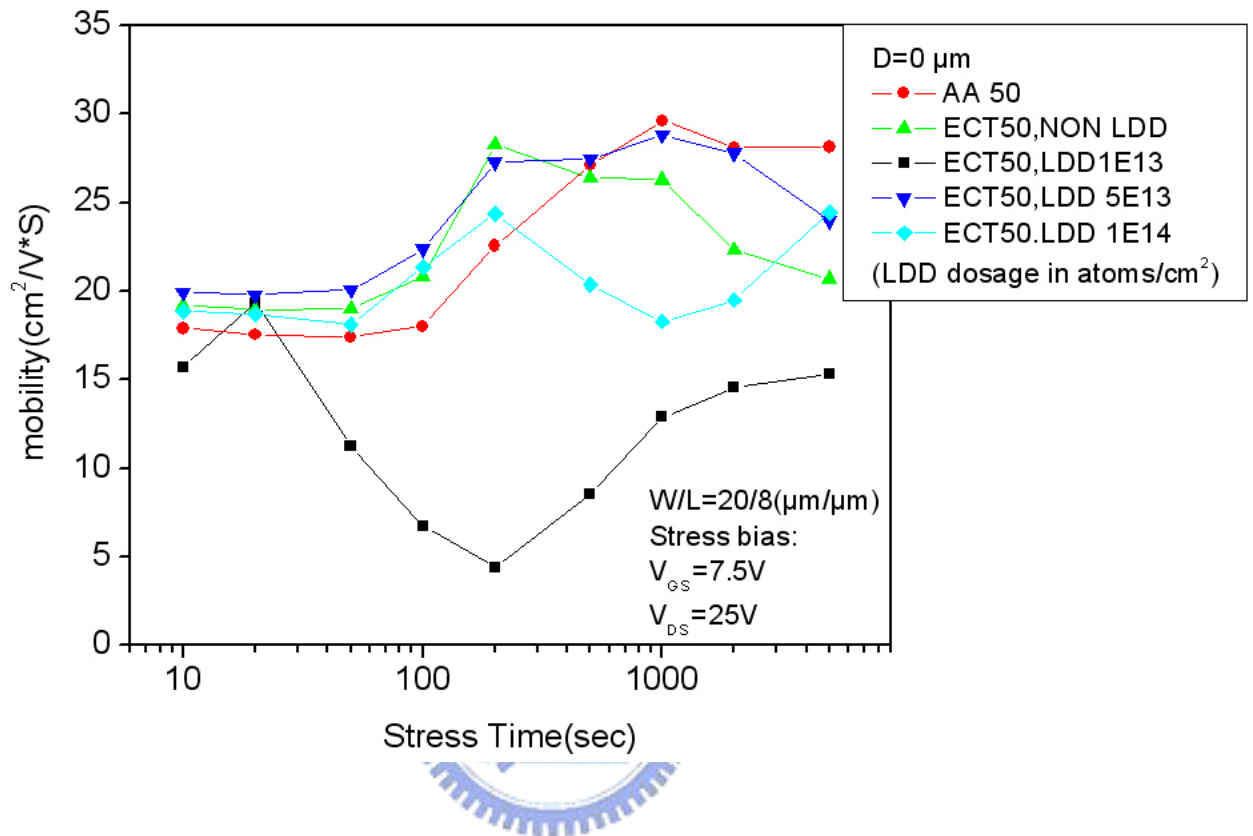


Figure 2-25 Variation of mobility at $V_{DS}=0.1\text{V}$ under hot carrier stress.

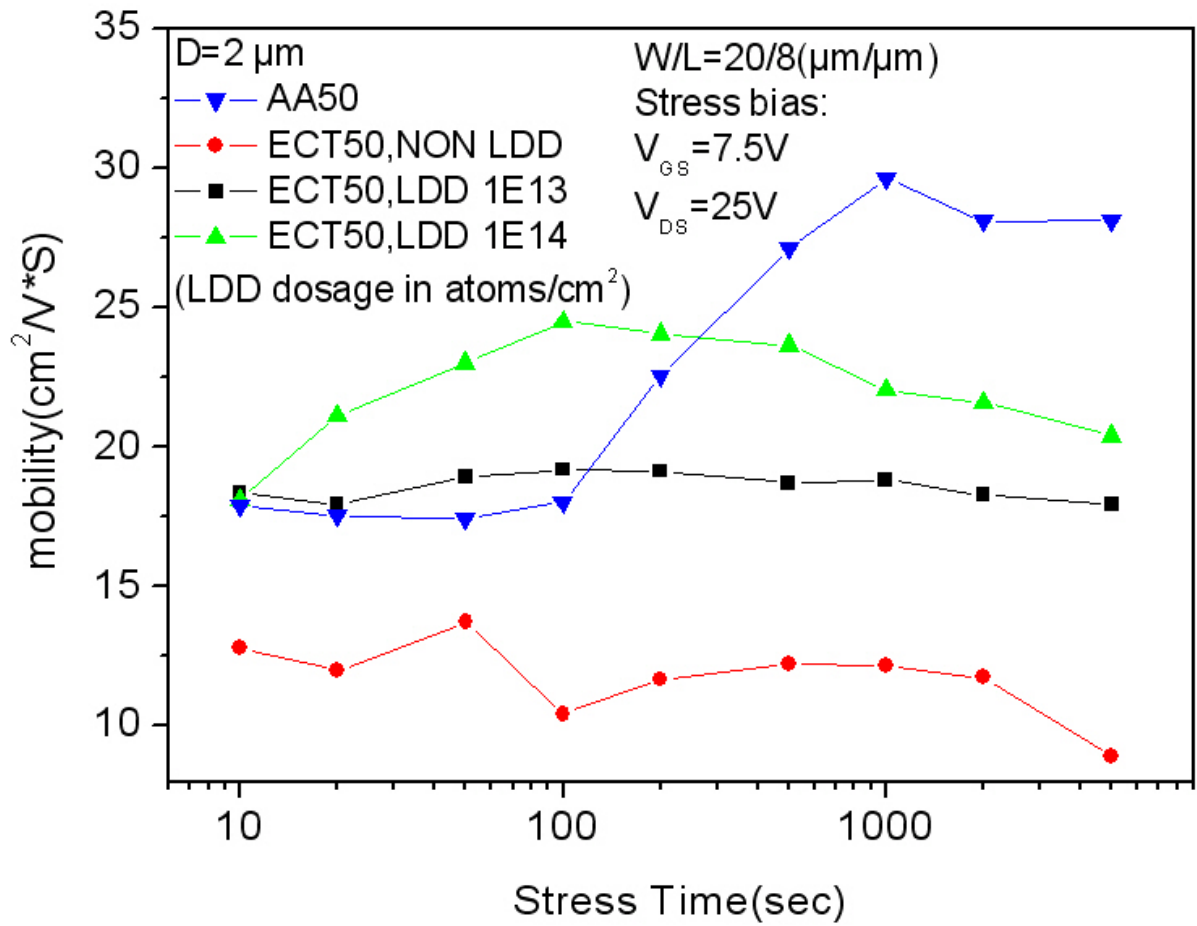


Figure 2-26 Variation of mobility at $V_{DS}=0.1\text{V}$ under hot carrier stress. $D(=2)$ is gate overlapping length.

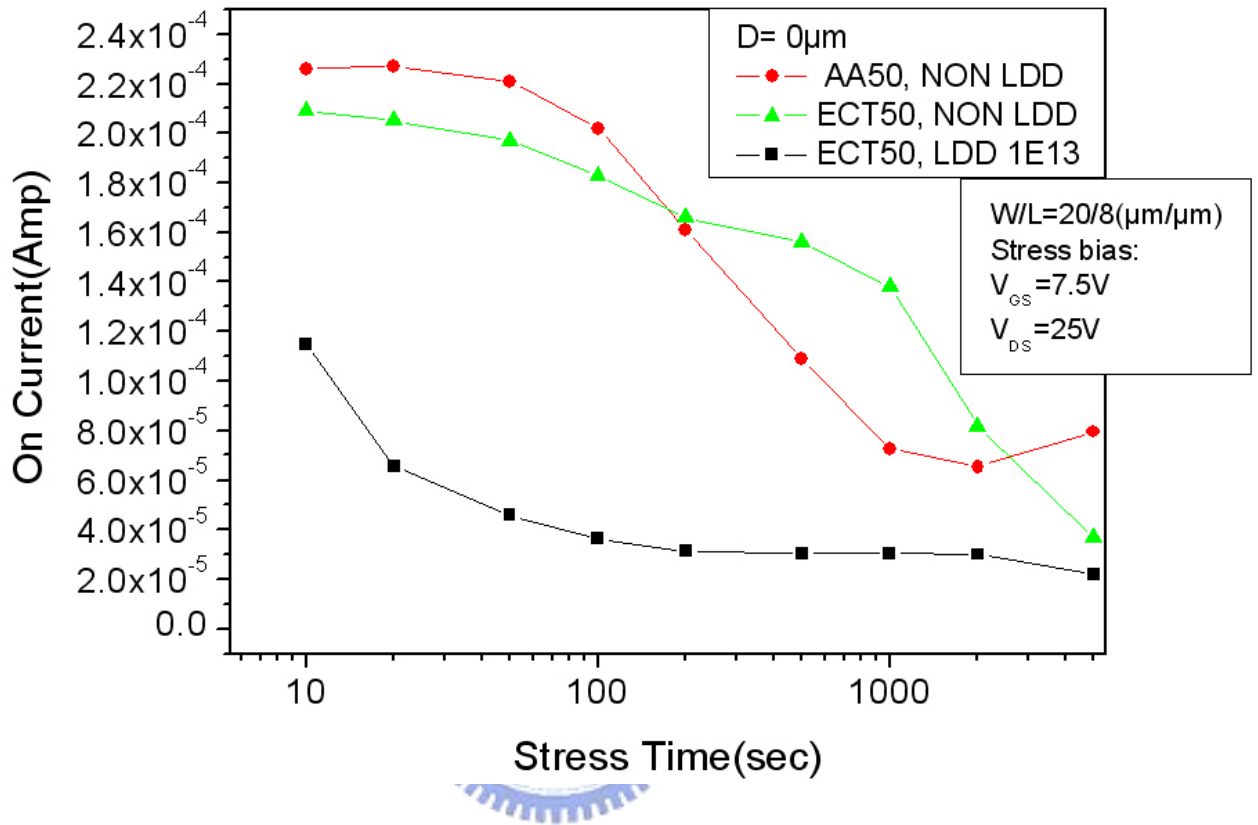


Figure 2-27 Variation of on current at $V_{DS}=5\text{V}$ under hot carrier stress.

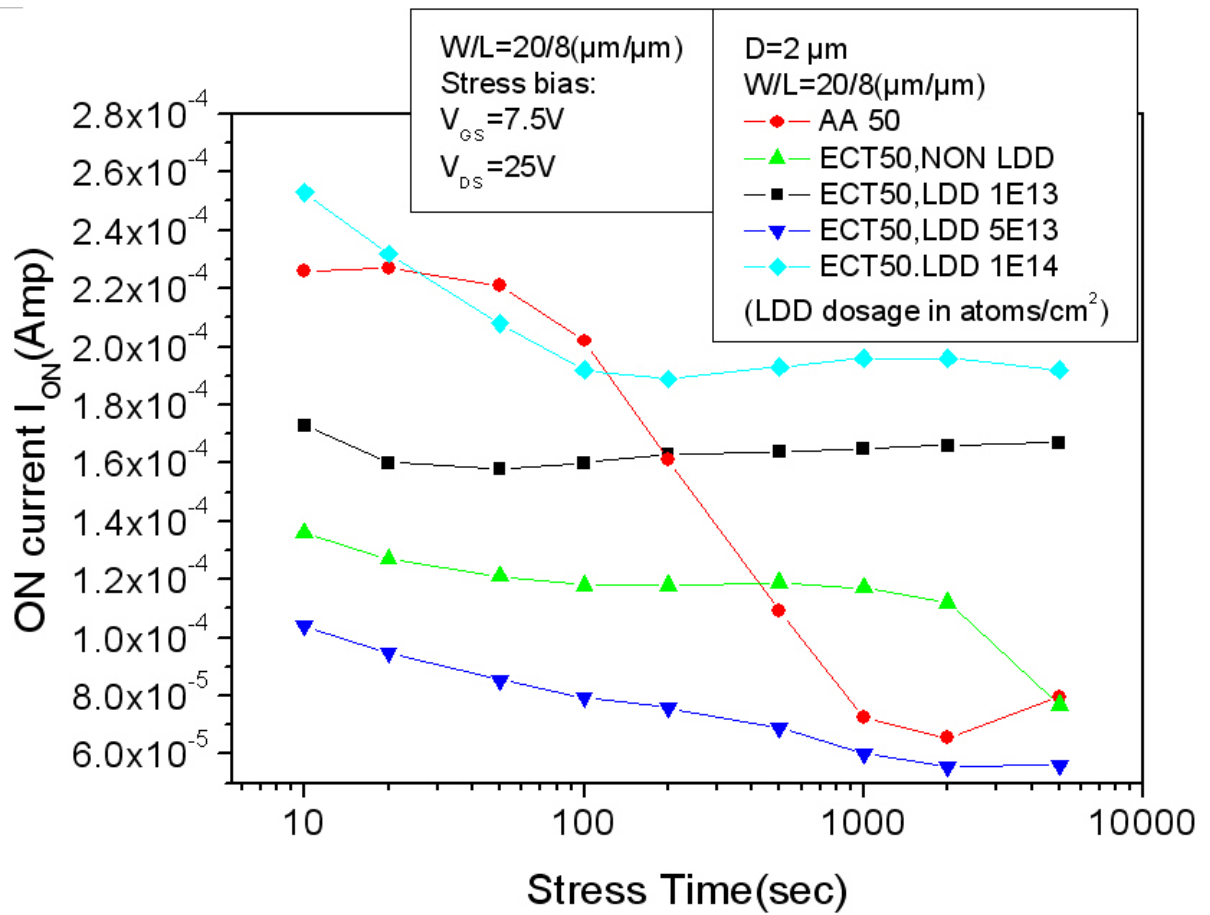


Figure 2-28 Variation of on current at $V_{DS}=5\text{V}$ under hot carrier stress. D(=2) is gate overlapping length.